

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Patent Application

Applicant(s): Roger Y.B. Young et al.

Serial No.: 10/628,614

Filing Date: July 28, 2003

Confirm. No.: 4439

Art Unit: 2878

Examiner: Que Tan Le

Title: Wafer Edge Defect Inspection Using Captured Image Analysis

AMENDMENT AND RESPONSE TO OFFICE COMMUNICATION

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313

Sir:

In response to the outstanding Office Communication dated March 24, 2011, Applicants respectfully request reconsideration of the above-identified application in view of the amendments made herein.